

EAST Search History**EAST Search History (Interference)**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L10	9	((detect\$3 sens\$3) near3 (immersion liquid fluid water) near3 (during parallel "same" adj time together simultaneous\$2) near3 (expos\$3 pattern\$3 project \$3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L11	49	((detect\$3 sens\$3) near1 (immersion liquid fluid water) near2 (expos\$3 pattern\$3 project \$3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L12	23	((detect\$3 sens\$3) near3 (immersion liquid fluid water) and (detect\$3 sens \$3) near3 (during parallel "same" adj time together simultaneous\$2) near3 (expos\$3 pattern\$3 project \$3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L13	517	((detect\$3 sens\$3) near3 (during parallel "same" adj time together simultaneous\$2) near3 (expos\$3 pattern\$3 project \$3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32

L14	1	((detect\$3 sens\$3) near3 (immersion liquid fluid water) same (load\$3 unload\$3) near2 (wafer substrate workpiece) and (\$5lithograph\$2 exposure)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L15	14	((detect\$3 sens\$3) near3 (immersion liquid fluid water) and (load\$3 unload \$3) near2 (wafer substrate workpiece) and (\$5lithograph\$2 exposure)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L16	28	((detect\$3 sens\$3) near3 (immersion liquid fluid water) and (load\$3 unload \$3) near2 (wafer substrate workpiece)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L17	0	((detect\$3 sens\$3) near (immersion liquid fluid water) with (table support chuck holder) same3 (load\$3 unload\$3) near (wafer substrate workpiece) with (table support chuck holder)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33

L18	0	((detect\$3 sens\$3 camera determin\$5) near3 (residual remain\$3 leftover undesir\$4 unwanted stray leak\$3) near (immersion liquid fluid water) and (load\$3 unload\$3) near (wafer substrate workpiece) with (table support chuck holder)). clm.	US- PGPUB; UPAD	OR	ON	2010/12/17 10:33
L19	0	((detect\$3 sens\$3) near (immersion liquid fluid water) with (table support chuck holder) and (load\$3 unload\$3) near (wafer substrate workpiece) with (table support chuck holder)). clm.	US- PGPUB; UPAD	OR	ON	2010/12/17 10:33
L20	0	((detect\$3 sens\$3) near (immersion liquid fluid water) with (table support chuck holder) and (load\$3 unload\$3) near (wafer substrate workpiece)).clm.	US- PGPUB; UPAD	OR	ON	2010/12/17 10:33

12/17/2010 10:36:07 AM

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imm detection light liq shape.wsp**